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CONFIRMATION NO. 1541

SERIAL NUMBER 09/889,838	FILING OR 371(c) DATE 01/24/2002 RULE	CLASS 216	GROUP ART UNIT 1763	ATTORNEY DOCKET NO. 10191/1808
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APPLICANTS
 Franz Laermer, Weil der Stadt, GERMANY;
 Andrea Schilp, Stuttgart, GERMANY;
**** CONTINUING DATA *******

This application is a 371 of PCT/DE00/03545 10/10/2000

**** FOREIGN APPLICATIONS *******

GERMANY 199 57 169 11/27/1999

IF REQUIRED, FOREIGN FILING LICENSE GRANTED**** 05/13/2004**

Foreign Priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no	STATE OR COUNTRY GERMANY	SHEETS DRAWING 3	TOTAL CLAIMS 21	INDEPENDENT CLAIMS 1
35 USC 119 (a-d) conditions met <input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance				
Verified and Acknowledged	Examiner's Signature	Initials		

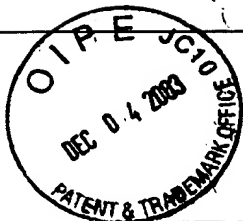
ADDRESS

26646

TITLE

Plasma etching method having pulsed substrate electrode power

FILING FEE RECEIVED 1436	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:	<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit
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DT06 Rec'd PCT/PTO 04 DEC 2003

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**REQUEST FOR CORRECTED FILING
RECEIPT**

Docket Number:
10191/1808

Application Number
09/899,838

Filing Date
January 24, 2002

Examiner
Allan Olsen

Art Unit
1763

Invention Title
PLASMA ETCHING METHOD HAVING PULSED
SUBSTRATE ELECTRODE POWER

Inventor(s)
Franz LAERMER et al.

Address to:
Commissioner of Patents
P.O. Box 1450
Alexander, VA 22313-1450

Applicants respectfully request that the filing receipt (a copy of which is attached) be corrected to show the title and the attorney docket no. to read:

PLASMA ETCHING METHOD HAVING PULSED SUBSTRATE ELECTRODE
POWER

10191/1808

Please issue a corrected filing receipt as requested above. If any fees are due they should be charged to Kenyon & Kenyon Deposit Account No. 11-0600.

Dated:

December 1, 2003

By:

Richard L. Mayer (Reg. No. 22,490)

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APPLICATION NUMBER	FILING DATE	GRP ART UNIT	FIL FEE REC'D	ATTY DOCKET NO	DRAWINGS	TOT CLAIMS	IND CLAIMS
09/889,838	01/24/2002	1746	1008	10191/808-1808	3	21	1

26646
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NEW YORK, NY 10004



CONFIRMATION NO. 1541

FILING RECEIPT



OC00000007475271

Date Mailed: 02/20/2002

Receipt is acknowledged of this nonprovisional Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Customer Service Center. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

Franz Laermer, Weil der Stadt, GERMANY;
Andrea Schilp, Stuttgart, GERMANY;

Domestic Priority data as claimed by applicant

THIS APPLICATION IS A 371 OF PCT/DE00/03545 10/10/2000

Foreign Applications

GERMANY 199 57 169 11/27/1999

Projected Publication Date: Not Applicable, filed prior to November 29,2000

Non-Publication Request: No

Early Publication Request: No

Title

Plasma etching method ^{having} giving pulsed substrate electrode power

Preliminary Class

216